

Notice of References CitedApplication No.
09/285,773Applicant(s)
Mercaldi et al.Examiner
Lynette T. Umez-EroniniGroup Art Unit
1765

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U.S. PATENT DOCUMENTS

	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS
A					
B					
C					
D					
E					
F					
G					
H					
I					
J					
K					
L					
M					

FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	NAME	CLASS	SUBCLASS
N	51123739A	10/1976	Japan	Mitsubishi Electronic Corp.	CO9K	13/08
O						
P						
Q						
R						
S						
T						

NON-PATENT DOCUMENTS

	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)	DATE
U	Mitsubiah Electric Corp., Etchant for silicon with minimal undercutting - of aq. hydrogen fluoride and nitric acid, with acid or organic cpd. of viscosity greater than water, English translation of JP 51123739 A	10/1976
V		
W		
X		